

(54) Title of the invention : SILICIDE ON OXIDE-BASED ELECTROSTATICALLY DOPED (SILO-ED) CARRIER SELECTIVE CONTACT-BASED PERC PHOTOVOLTAIC DEVICE

(51) International classification :H01L0031180000, H01L0031021600, H01L0031022400, H01L0031035200, H01L0031068000

(86) International Application No :NA
Filing Date :NA

(87) International Publication No : NA

(61) Patent of Addition to Application Number :NA
Filing Date :NA

(62) Divisional to Application Number :NA
Filing Date :NA

(71)Name of Applicant :**1)Chitkara Innovation Incubator Foundation**

Address of Applicant :SCO: 160-161, Sector - 9c, Madhya Marg, Chandigarh - 160009, India. -----

Name of Applicant : NA**Address of Applicant : NA****(72)Name of Inventor :****1)KASHYAP, Savita**

Address of Applicant :Research Scholar, Department of Electronics & Communication Engineering, Chitkara University, Chandigarh-Patiala National Highway, Village Jansla, Rajpura, Punjab - 140401, India. -----

2)PANDEY, Rahul

Address of Applicant :Assistant Professor, Department of Electronics & Communication Engineering, Chitkara University, Chandigarh-Patiala National Highway, Village Jansla, Rajpura, Punjab - 140401, India. -----

3)MADAN, Jaya

Address of Applicant :Assistant Professor, Department of Electronics & Communication Engineering, Chitkara University, Chandigarh-Patiala National Highway, Village Jansla, Rajpura, Punjab - 140401, India. -----

4)SHARMA, Rajnish

Address of Applicant :Professor, Department of Electronics & Communication Engineering, Chitkara University, Chandigarh-Patiala National Highway, Village Jansla, Rajpura, Punjab - 140401, India. -----

(57) Abstract :

The present disclosure relates to a silicide on oxide-based electrostatically doped (SILO-ED) carrier selective contact-based passivated emitter and rear contact (PERC) photovoltaic device. The device includes an upright pyramid-based textured PERC solar cell to enhance light trapping within the substrate. Further, Erbium silicide (ErSi₂) having a work function $m=3$ eV is used, where, ErSi₂ is directly deposited onto an interfacial oxide layer to avoid the need for actual physical doping. The interfacial oxide layer is SiO₂ of thickness 1.5 nm for tunneling of charge carriers. The front surface of the device includes dielectric stacks of SiNX (70 nm)/SiO₂ (10 nm) materials, which are used for antireflection coating and front surface passivation by reducing the optical and front side recombination loss. Further, the rear surface of the device includes dielectric stacks of Al₂O₃ (50 nm)/SiO₂ (40 nm) materials, which are used for rear surface passivation by reducing the recombination of charge carriers.

No. of Pages : 19 No. of Claims : 10